

# Analysis methods for meso- and macroporous silicon etching baths

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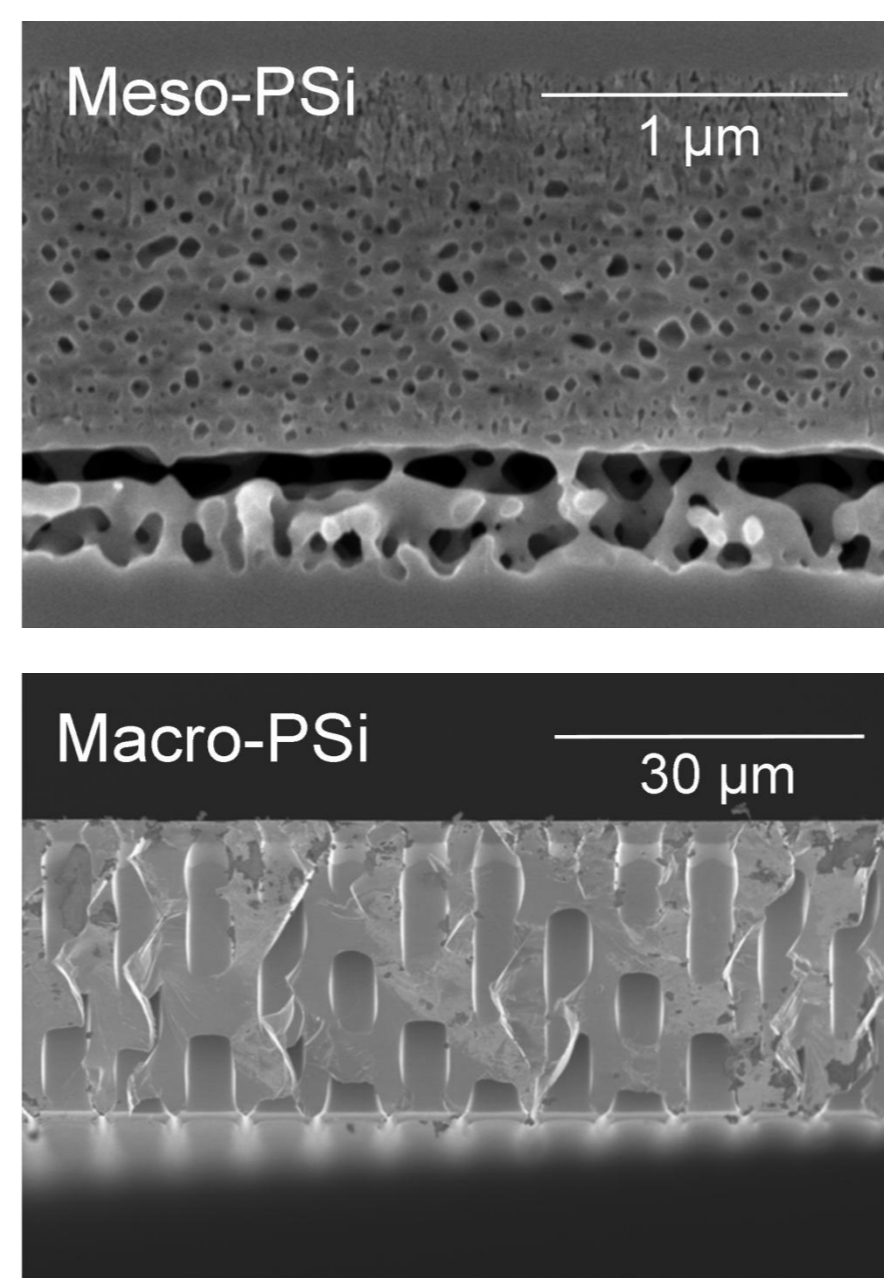
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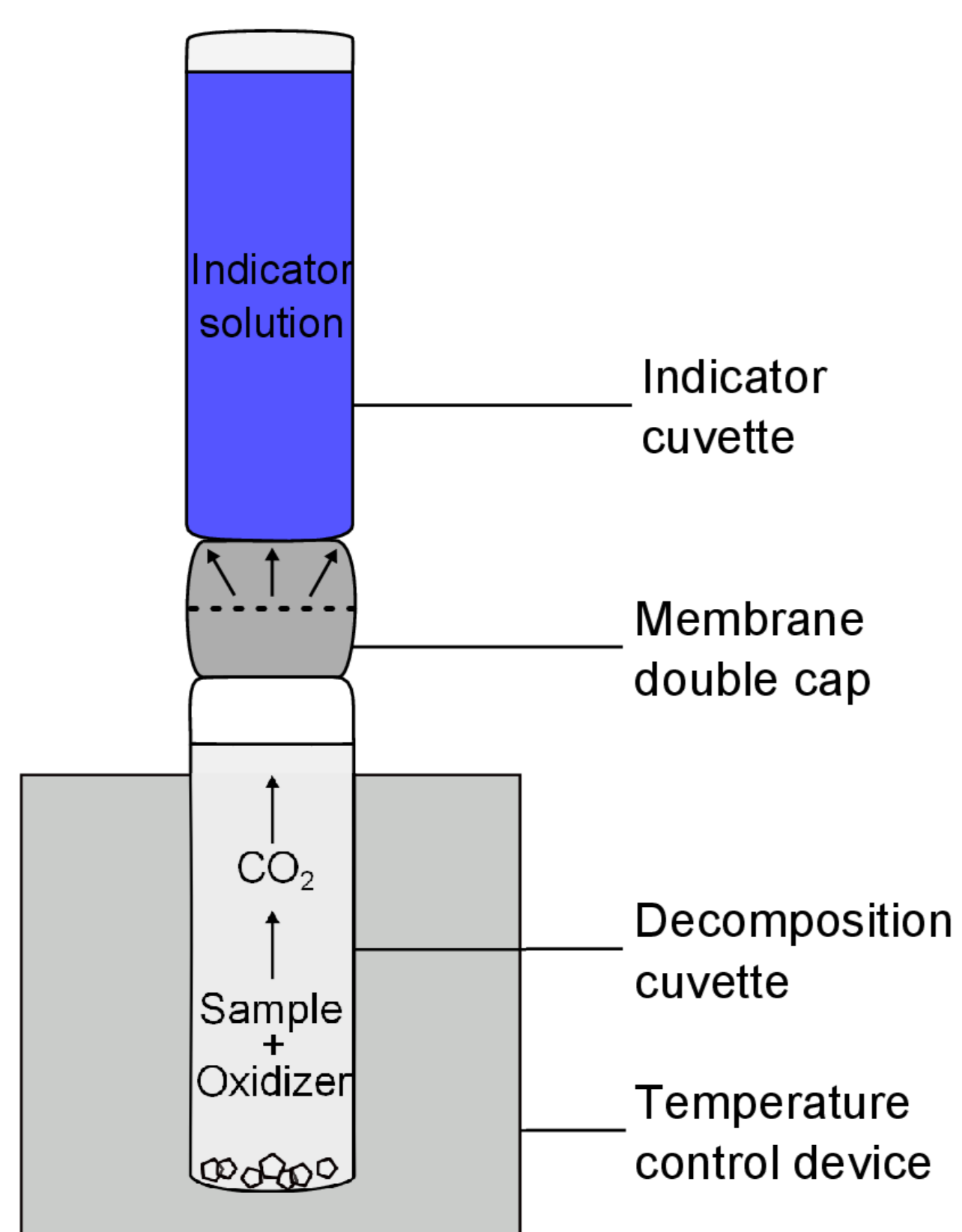


## Motivation

- Analysis of etching baths for porous silicon (PSi):  
Meso-PSi: HF (19.5 mol·L<sup>-1</sup>) + ethanol  
Macro-PSi: HF (1.5 mol·L<sup>-1</sup>) + acetic acid
- Constant process conditions for homogeneous pore formation  
→ Requires analysis of chemical composition of electrolytes
- Methods for determination of HF and organic contents described



## Determination of Organics



Observed color changes: 0 ppm, 10 ppm, 25 ppm, 35 ppm, 50 ppm TOC (from left to right).

### Cuvette test system:

- By HACH LANGE
- Analysis of wetting agents ethanol and acetic acid
- Determination of "Total Organic Carbon" = TOC  
→ Measurement range: 2 – 65 ppm TOC  
→ Relative error: 2.3%

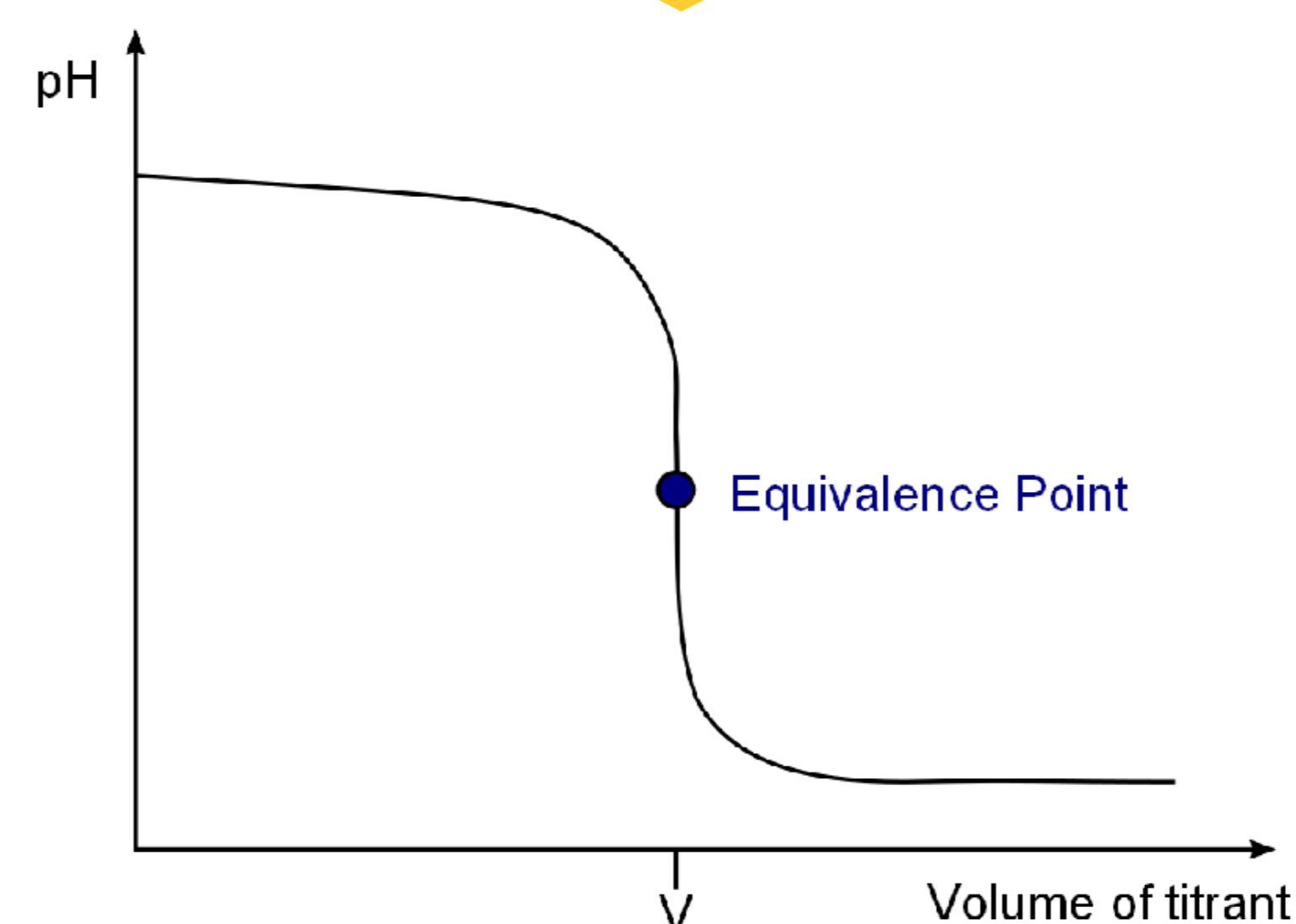
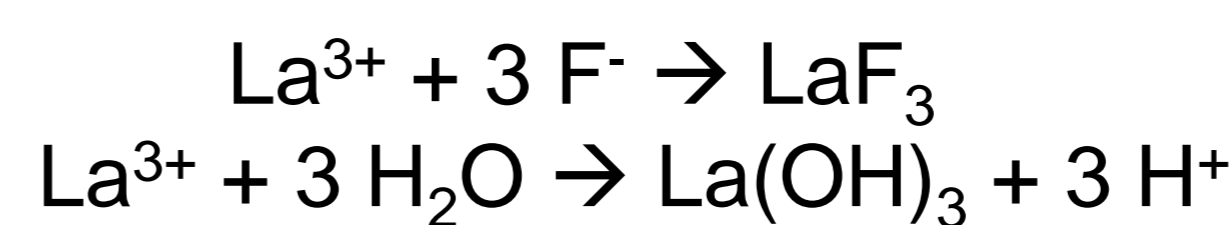
Heating the sample at 100 °C for 2 hours sets CO<sub>2</sub> free and leads to a color change of the indicator solution.

P. Prütz, "TOC wastewater analysis".  
Hach Lange. www.hach-lange.de.

## Determination of HF

### Titration:

- Adjustment to pH 6.5 – 7.5 with NaOH
- Titration with La(NO<sub>3</sub>)<sub>3</sub> for determination of HF

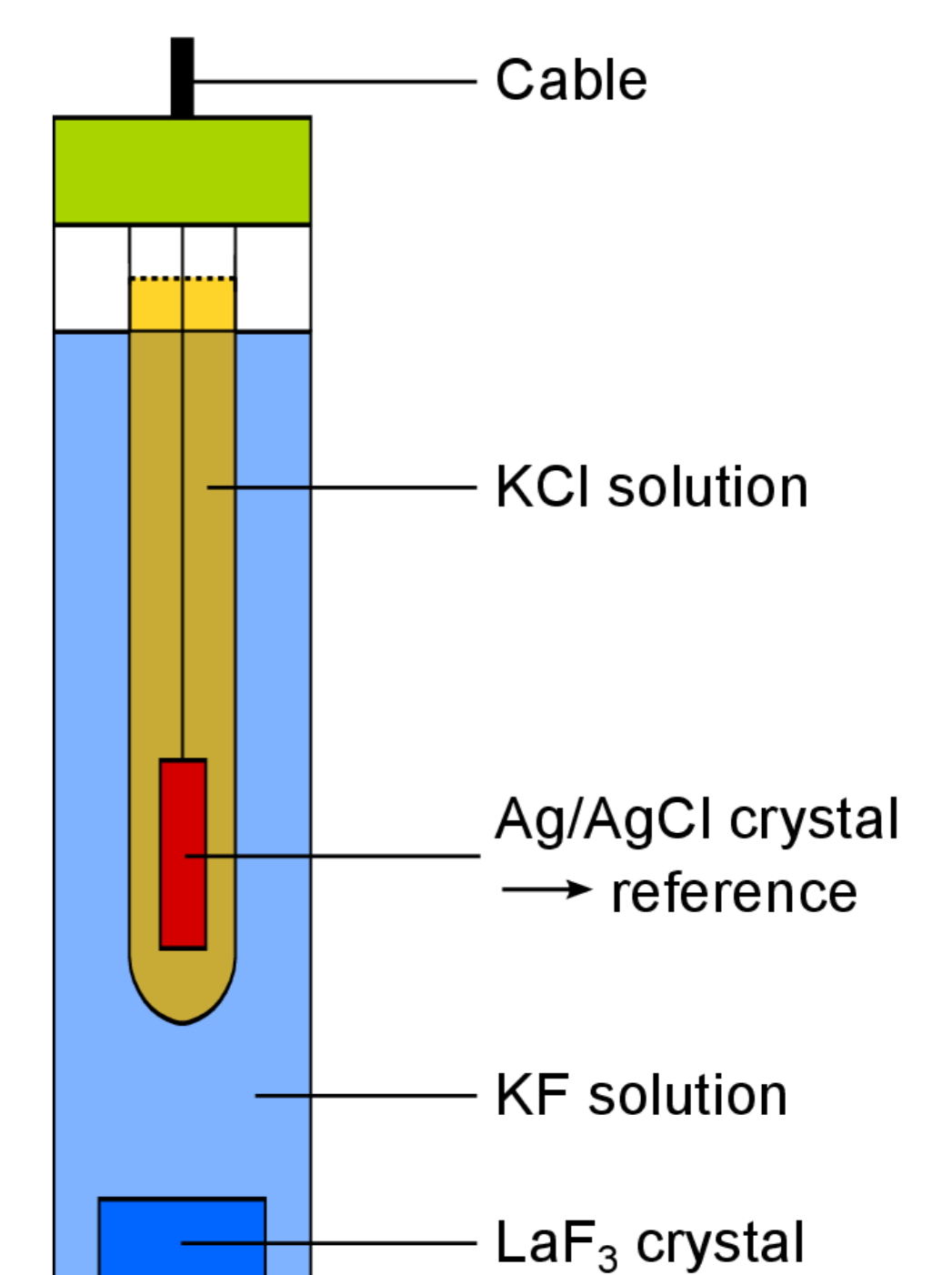


The volume of the titrant at the equivalence point is used for the calculation of the HF concentration.

W. Weinreich et al. *Talanta* **71**, 2007, 1901-1905.

### Fluoride Ion-Selective Electrode:

→ Direct measurement of HF in sample

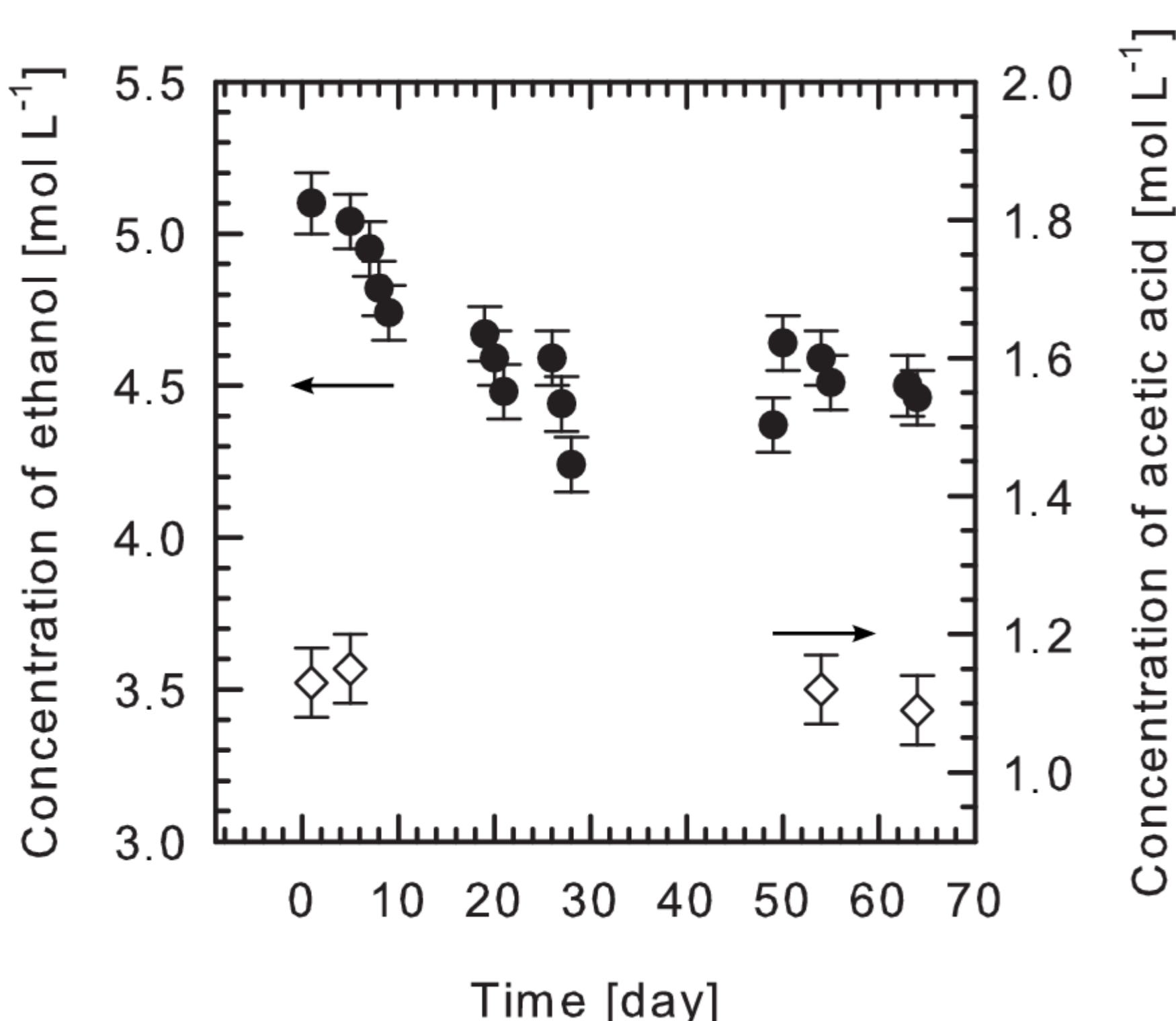


Schematic diagram of a Fluoride Ion-Selective Electrode (F-ISE).

Parameter	Titration	F-ISE
Measurement method	Indirect	Direct
Measurement range	> 50 mmol·L <sup>-1</sup>	0.05 – 50 mmol·L <sup>-1</sup>
Time for measurement	15 min	5 min
Time for calibration	5 min <sup>a</sup>	15 min <sup>b</sup>
Suitable for acetic acid containing electrolytes?	No	Yes
Relative error	± 3.3%	± 1.5%
Standard deviation (40 samples)	± 0.3%	± 0.3%
Inline analysis possible?	Yes	Yes

<sup>a</sup>once a week      <sup>b</sup>directly before measurement

## Application to Etching Baths for Porous Silicon

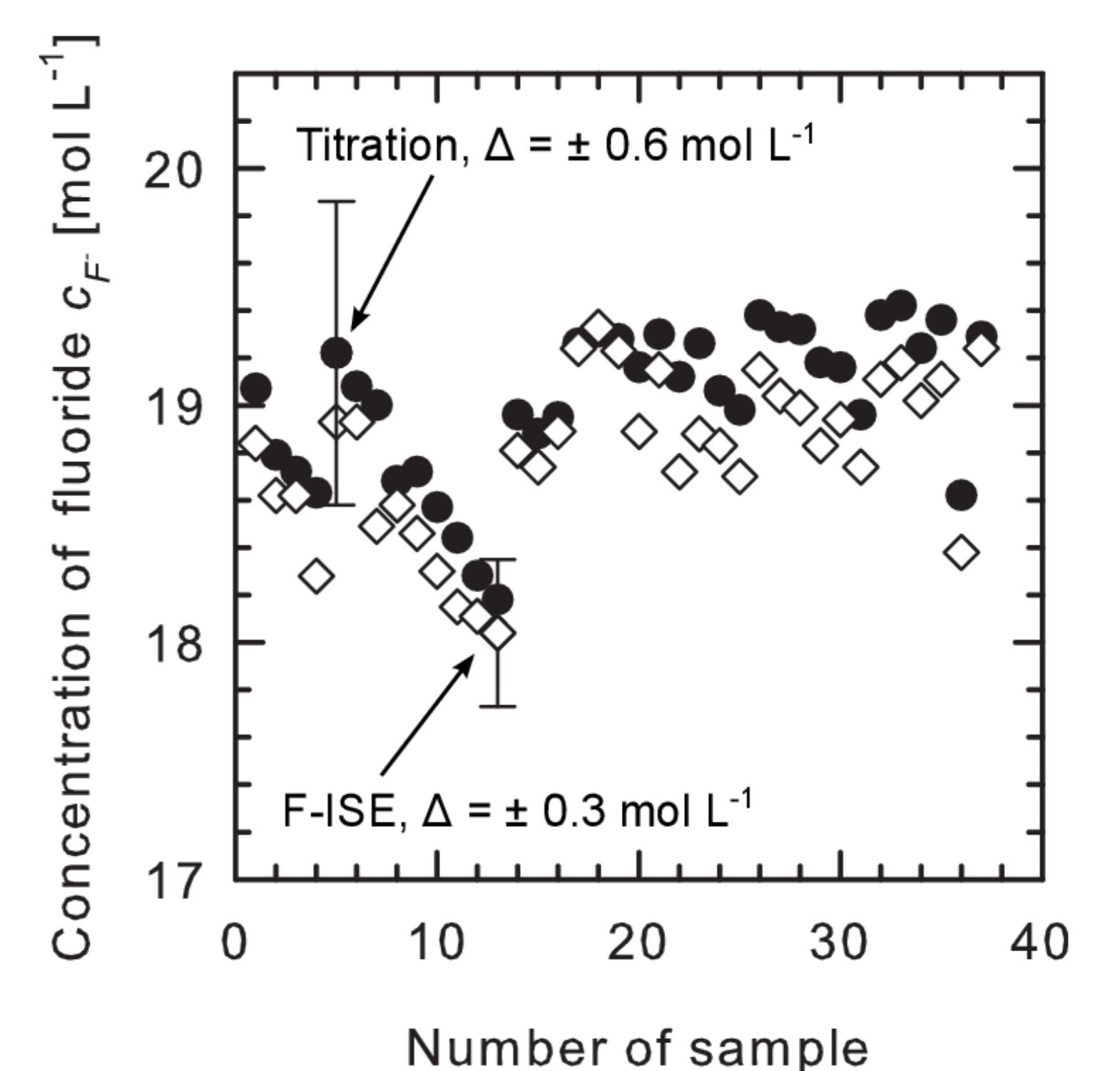


Development of organic contents in Meso- and Macro-PSi baths over time.

- Monitoring the constituents of the etching baths for porous silicon over time
- Meso-PSi: Titration, cuvette test method
- Macro-PSi: F-ISE, cuvette test method
- Loss of HF due to evaporation during etching
- Enlargement of bath lifetime due to replenishment of HF

### Conclusion:

- Keeping etching parameters constant due to stable HF concentration
- Constant process conditions achieved
- Homogeneous pore formation



Comparison of HF concentrations determined by titration and F-ISE.